WHAT IS CLAIMED IS:

- 1. A conveyor device for a flexible substrate, said conveyor device comprising:
- a conveying means for continuously conveying a flexible substrate from one end to the other end;
- a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;

wherein center axes of the plurality of cylindrical rollers run parallel to each other; and

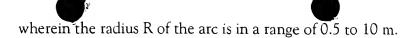
- a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.
 - 2. A device according to claim 1,

wherein the radius R of the arc is in a range of 0.5 to 10 m.

- 3. A film formation apparatus for a flexible substrate, said film formation apparatus comprising:
- a conveying means for continuously conveying a flexible substrate from one end to the other end;
 - a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;
- wherein center axes of the plurality of cylindrical rollers run parallel to each other; and
 - a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.
 - 4. An apparatus according to claim 3,

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- 5. An apparatus according to claim 3 further comprising:

 a vacuum chamber;

 an introducing means for introducing a gas into the vacuum chamber;

 a gas evacuation means; and
- an energy supplying means for supplying an energy to make a plasma from the gas.
 - 6. An apparatus according to claim 3, wherein the film formation apparatus is a plasma CVD apparatus.
- 7. An apparatus according to claim 5, wherein the energy is an electromagnetic wave.